



Appl. No. 09/360,292

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RECEIVED

NOV 03 2003

GROUP 1700

Application Serial No. 09/360,292
Filing Date July 22, 1999
Inventor..... Sujit Sharan et al.
Assignee..... Micron Technology, Inc.
Group Art Unit..... 1765
Examiner Ahmed, Shamim
Attorney's Docket No. MI22-1106
Title: Plasma Etching Process

RESPONSE TO JUNE 27, 2003 FINAL OFFICE ACTION TO ACCOMPANY RCE FILING

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

AMENDMENTS

Introductory Comments

In response to the Office Action dated June 27, 2003, applicant amends and remarks as follows.